

IN THE CLAIMS:

Please amend claim 1 as follows:

1. (Currently Amended) A wafer boat for supporting silicon wafers, the wafer boat comprising:

 a ceramic body having at least one wafer support structure sized to support a silicon wafer thereon;

 a ceramic coating disposed on a surface of the wafer support structure, the ceramic coating having an impurity migration preventing thickness that is substantially [between 30 and 60 microns] greater than or equal to 30 microns and a wafer contact surface, the wafer contact surface having a post coating surface finish;

 wherein the post coating surface finish of the wafer contact surface substantially prevents frictional slip in the silicon wafers and is less than or substantially equal to [0.4] 1.0 microns.

2. (Original) The wafer boat of Claim 1 wherein the wafer structure comprises at least one wafer slot sized to receive a silicon wafer therein.

3. (Original) The wafer boat of Claim 1 wherein the post coating surface finish of the wafer contact surface substantially prevents slip in silicon wafers of 300mm diameter or greater.

4. (Original) The wafer boat of Claim 1 wherein the post coating surface finish of the wafer contact surface substantially prevents slip in silicon wafers during the thermal operations reaching temperatures of 720 degrees centigrade or greater.

5. (Original) The wafer boat of Claim 1 wherein the ceramic body comprises one of quartz, silicon carbide (SiC) and recrystallized SiC.
6. (Original) The wafer boat of Claim 1 wherein the ceramic coating comprises a SiC.
7. Claim 7 cancelled
8. Claim 8 cancelled.
9. (Previously Amended) The wafer boat of Claim 1 wherein the ceramic coating has an impurity level of substantially 1 ppm or less.
10. Claim 10 cancelled.
11. (Original) The wafer boat of Claim 1 wherein the wafer boat is a vertical wafer boat.
12. (Original) The wafer boat of Claim 2 comprising:
a generally horizontal base;
a support rod extending generally vertically from the base and having at least a pair of arms extending generally parallel relative to the base, the pair of arms defining the at least one wafer slot.
13. (Original) The wafer boat of Claim 12 wherein the support rod comprises a plurality of arms defining a plurality of slots each sized to receive a silicon wafer, each slot having the ceramic coating disposed thereon to define a plurality of wafer contact surfaces, each wafer contact surface having the post coating surface finish.
14. (Original) The wafer boat of Claim 12 wherein the support rod comprises a plurality of support rods.
15. (Original) The wafer boat of Claim 12 comprising a top plate attached to the upper distal end of the support rod.

16. (Original) The wafer boat of Claim 12 wherein the base comprises a stress relief slot and a location notch.
17. Claim 17 withdrawn.
18. Claim 18 withdrawn.
19. Claim 19 withdrawn.
20. Claim 20 withdrawn.
21. Claim 21 withdrawn.
22. Claim 22 withdrawn.
23. Claim 23 withdrawn.
24. Claim 24 withdrawn.
25. Claim 25 withdrawn.
26. Claim 27 withdrawn.
27. Claim 27 withdrawn.
28. Claim 28 withdrawn.

29. (Previously Amended) The wafer boat of Claim 1 comprising:
a base;
a plurality of support rods extending generally upwards from the base, each support rod including at least one arm extending generally inwardly relative to the base, each arm having the post coating surface finish disposed thereon.

Please amend claim 30 as follows:

30. (Currently Amended) A wafer boat for supporting silicon wafers while substantially eliminating friction slip in said silicon wafers, the wafer boat comprising:

a ceramic body having at least one wafer support structure sized to support a silicon wafer thereon;

a ceramic coating disposed on a surface of the wafer support structure, the ceramic coating having an impurity migration preventing thickness that is substantially between 30 to [40] 60 microns and a wafer contact surface, the wafer contact surface having a post coating surface finish;

wherein the post coating surface finish is less than or substantially equal to 0.4 microns.

31. (Cancelled)

32. (Previously Added) The wafer boat of Claim 30 comprising:

 a base;

 a plurality of support rods extending generally upwards from the base, each support rod including at least one arm extending generally inwardly relative to the base, each arm having the post coating surface finish disposed thereon.